	Application No.	Applicant(s)	
Notice of Allowability	10/631,331	SUNG, CHAE GEE	
	Examiner	Art Unit	.1
	Edgardo Ortiz	2815	AN
The MAILING DATE of this communication appears on the cover sheet with the correspondence address All claims being allowable, PROSECUTION ON THE MERITS IS (OR REMAINS) CLOSED in this application. If not included herewith (or previously mailed), a Notice of Allowance (PTOL-85) or other appropriate communication will be mailed in due course. THIS NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RIGHTS. This application is subject to withdrawal from issue at the initiative of the Office or upon petition by the applicant. See 37 CFR 1.313 and MPEP 1308.			
1. This communication is responsive to a preliminary amendment filed July 31, 2003.			
2. The allowed claim(s) is/are 6-9.			
3. The drawings filed on 31 July 2003 are accepted by the Examiner.			
 4. Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f). a) All b) Some* c) None of the: Certified copies of the priority documents have been received. Certified copies of the priority documents have been received in Application No. 09/413,653. Copies of the certified copies of the priority documents have been received in this national stage application from the International Bureau (PCT Rule 17.2(a)). * Certified copies not received: 			
Applicant has THREE MONTHS FROM THE "MAILING DATE" of this communication to file a reply complying with the requirements noted below. Failure to timely comply will result in ABANDONMENT of this application. THIS THREE-MONTH PERIOD IS NOT EXTENDABLE.			
5. A SUBSTITUTE OATH OR DECLARATION must be submitted. Note the attached EXAMINER'S AMENDMENT or NOTICE OF INFORMAL PATENT APPLICATION (PTO-152) which gives reason(s) why the oath or declaration is deficient.			
 6. CORRECTED DRAWINGS (as "replacement sheets") must be submitted. (a) including changes required by the Notice of Draftsperson's Patent Drawing Review (PTO-948) attached 1) hereto or 2) to Paper No./Mail Date (b) including changes required by the attached Examiner's Amendment / Comment or in the Office action of Paper No./Mail Date Identifying indicia such as the application number (see 37 CFR 1.84(c)) should be written on the drawings in the front (not the back) of each sheet. Replacement sheet(s) should be labeled as such in the header according to 37 CFR 1.121(d). 			
7. DEPOSIT OF and/or INFORMATION about the deposit of BIOLOGICAL MATERIAL must be submitted. Note the attached Examiner's comment regarding REQUIREMENT FOR THE DEPOSIT OF BIOLOGICAL MATERIAL.			
 Attachment(s) 1. ☑ Notice of References Cited (PTO-892) 2. ☐ Notice of Draftperson's Patent Drawing Review (PTO-948) 3. ☐ Information Disclosure Statements (PTO-1449 or PTO/SB/0 Paper No./Mail Date	5. Notice of Informal F 6. Interview Summary Paper No./Mail Da 8), 7. Examiner's Amend 8. Examiner's Statem 9. Other	r (PTO-413), tte ment/Comment	

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DETAILED ACTION

Allowable Subject Matter

1. The following is an examiner's statement of reasons for allowance: The cited prior art fails to disclose, teach or suggest, at least on claim 6, a thin film apparatus including "bringing said reactive gas into a plasma state under a first radio-frequency electric field formed between said radio-frequency electrode and said susceptor electrode, thereby forming a first coating on said substrate; and bringing said reactive gas into a plasma state under a greater second radio-frequency electric field than said first radio-frequency electric field while maintaining the plasma state between said radio-frequency electrode and said susceptor electrode, thereby forming a second coating on the surface of said first coating". And at least on claim 9, a thin film apparatus including "bringing said first gas mixture into a plasma state under a first radiofrequency electric field formed between said radio-frequency electrode and said susceptor electrode, thereby forming a first silicon nitride film on said substrate; and supplying a second gas mixture of monosilane gas and ammonia, which are mixed at such a second mixing ratio as containing the ammonia gas at a greater proportion than at said first mixing ratio, to the inner space of said film forming chamber while maintaining the plasma state between said radio-frequency electrode and said susceptor electrode, thereby forming a second silicon nitride film on the surface of said first silicon nitride film ".

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Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

Conclusion

2. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Edgardo Ortiz whose telephone number is 571-272-1735, or by fax at 571-273-1735. The examiner can normally be reached on Monday-Friday (1st Friday Off).

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Tom Thomas can be reached on 571-272-1664. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

8/7/04

PRIMARY EXAMINER